



MIT 3.071

Amorphous Materials

11: Amorphous Silicon Macroelectronics

Juejun (JJ) Hu

Electron's travels: from Lilliput to Brobdingnag

Microelectronics
"Smaller is smarter"

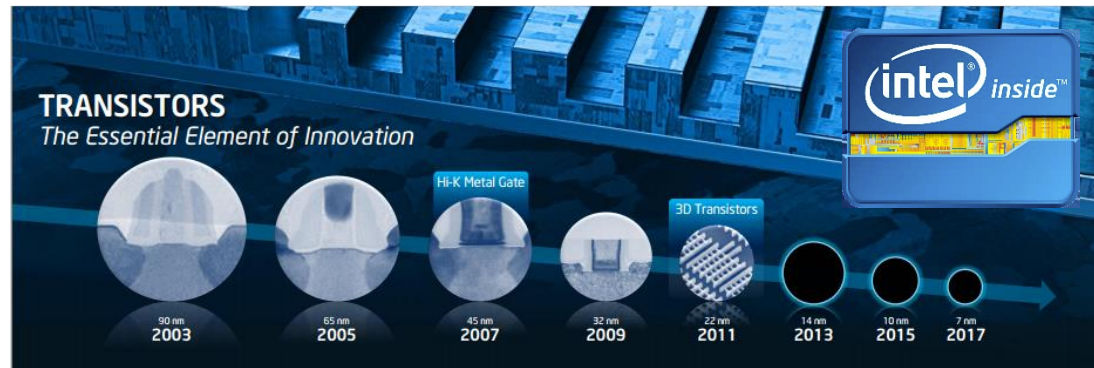


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Macroelectronics
"Bigger is better"



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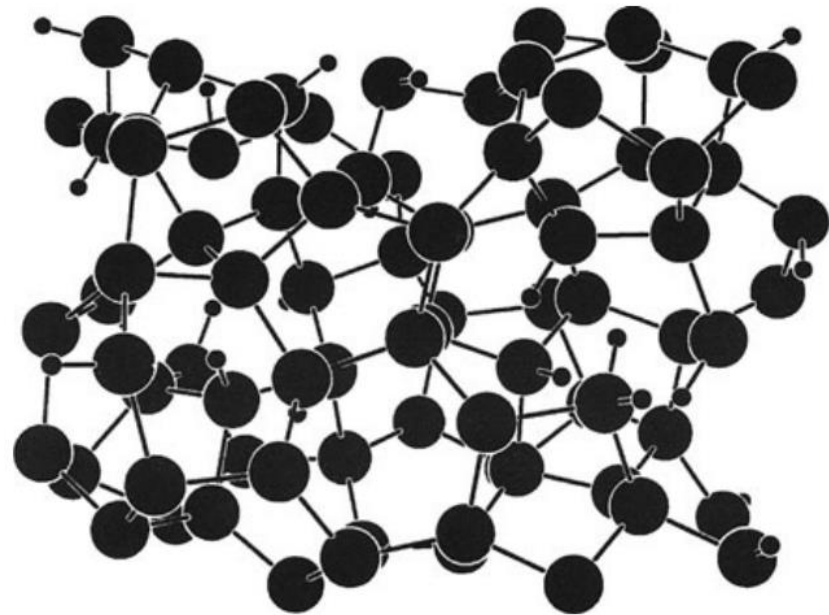
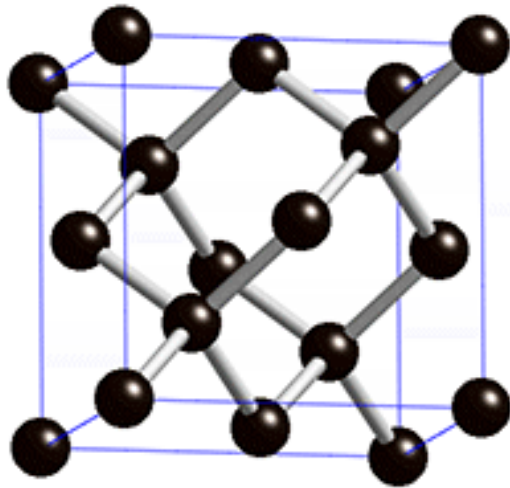
Why amorphous silicon?

- Large-area, low-temperature, monolithic deposition
 - Low-cost, mature PECVD process
 - Dielectrics and passivation layers can be formed using the same process
- Doping capacity
 - Effective passivation of defects (hydrogenation)
- CMOS compatibility
 - Leveraging existing infrastructure and knowledge base from the microelectronics industry

“The essence of being human is that one does not seek perfection.”

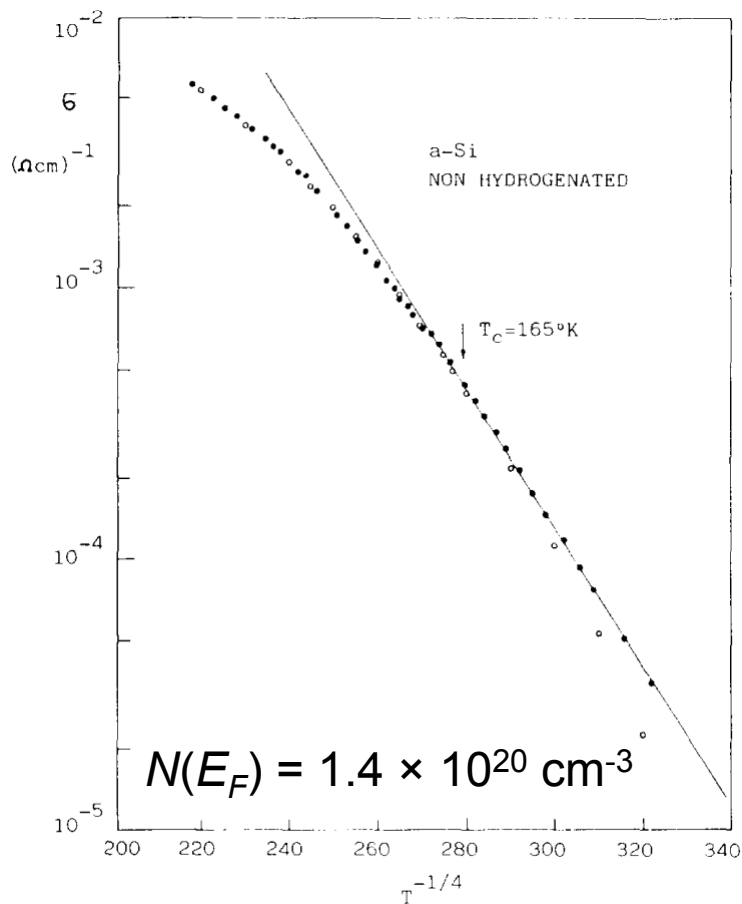
-- George Orwell

Structure of amorphous silicon



- c-Si: diamond structure consisting of 6-member rings formed by 4-fold coordinated Si atoms
- a-Si: continuous random network consisting of rings of varying sizes formed by mostly 4-fold coordinated Si atoms

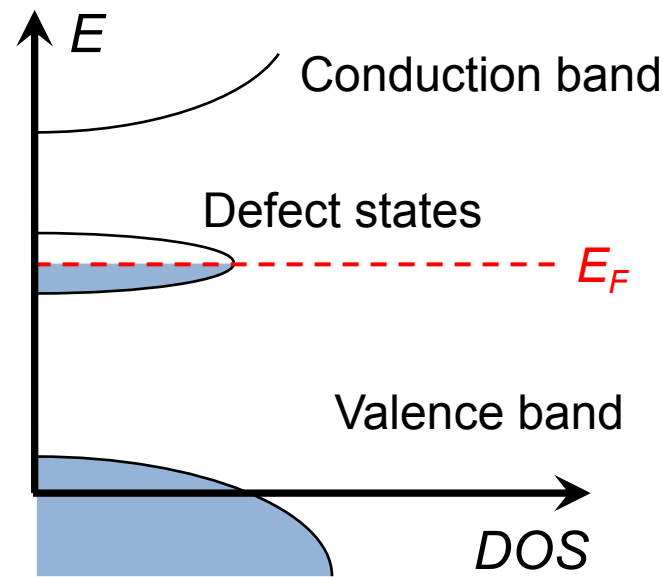
Hydrogen passivation (hydrogenation)



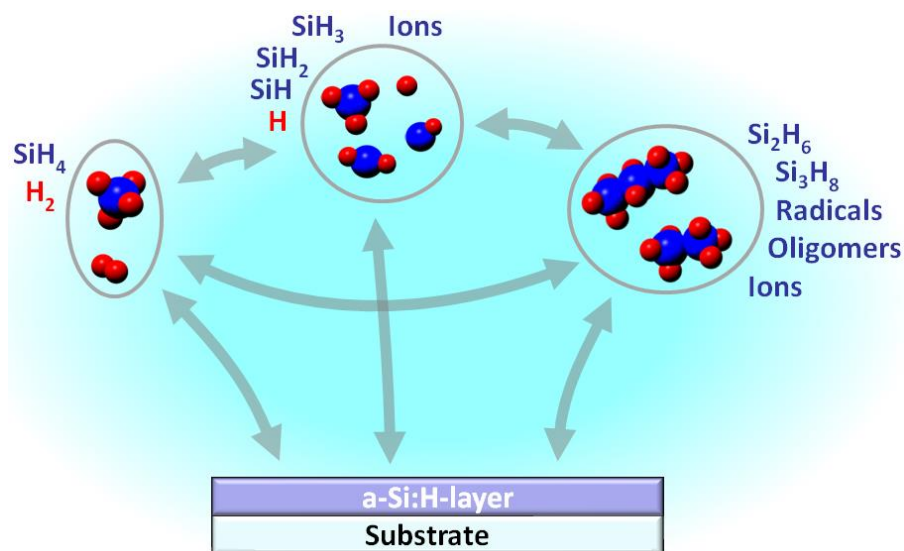
Courtesy of Elsevier, Inc., <http://www.sciencedirect.com>.
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Source: D'Amico, A. and G. Fortunato. "Conductivity and Noise in Thin Films of Nonhydrogenated Amorphous Silicon in the Hopping Regime." *Solid-state Electronics* 28, no. 8 (1985): 837-844.

- Pure a-Si has large deep level defect density
- Unpassivated dangling bonds: recombination centers
- Fermi level pinning



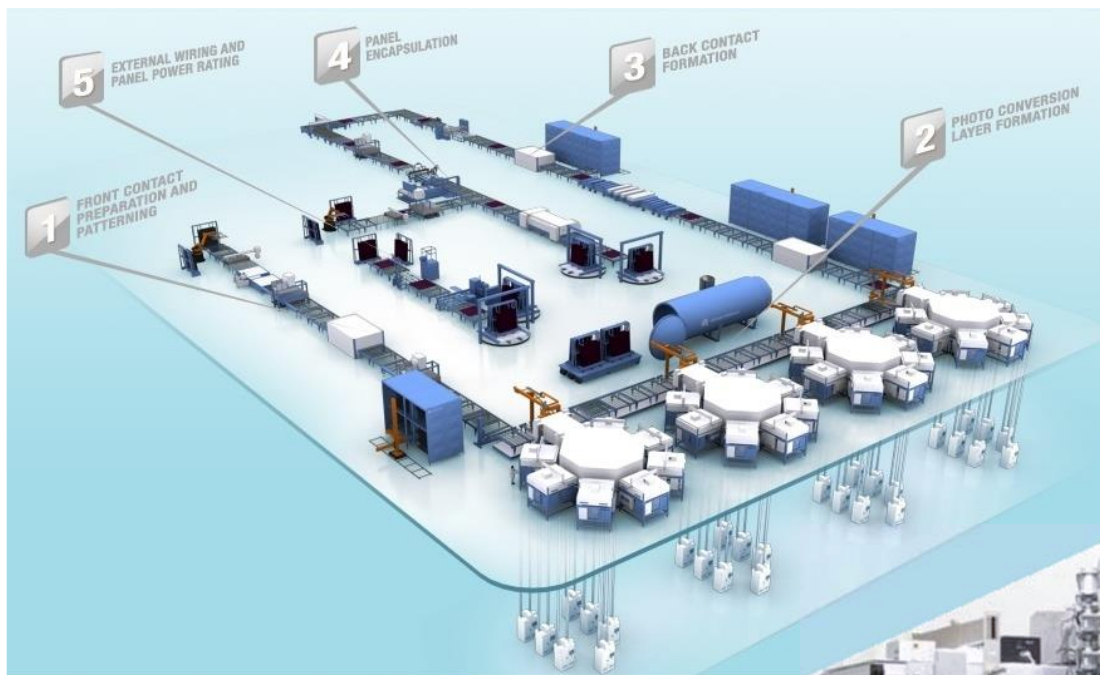
Hydrogen passivation (hydrogenation)



Figures removed due to copyright restrictions.
See Figures 26.4, 26.18: *Springer Handbook of Electronic and Photonic Materials*. Kasap, S. and P. Capper (Eds.). Springer, 2007.

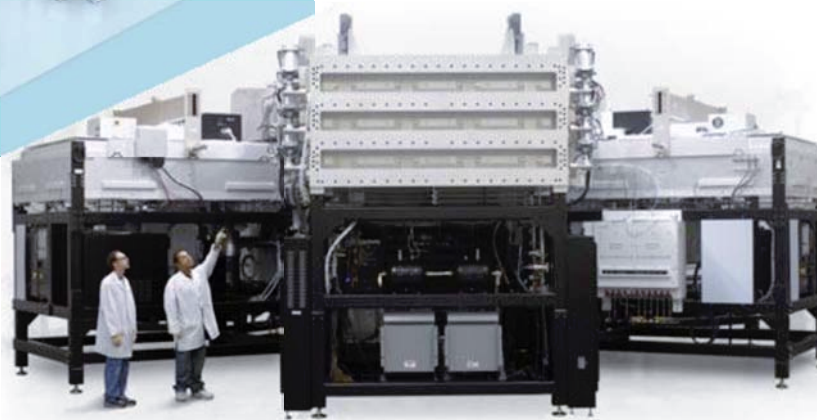
- $\text{SiH}_4 \rightarrow \text{a-Si:H} + \text{H}_2$
- Dangling bond formation on a-Si:H surface due to H removal by adsorbed SiH₃ radicals

Large-area PECVD a-Si:H deposition



Applied SunFab
Thin Film Line

Glass substrate size: **5.7 m²**

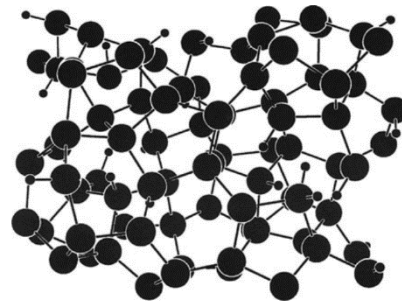
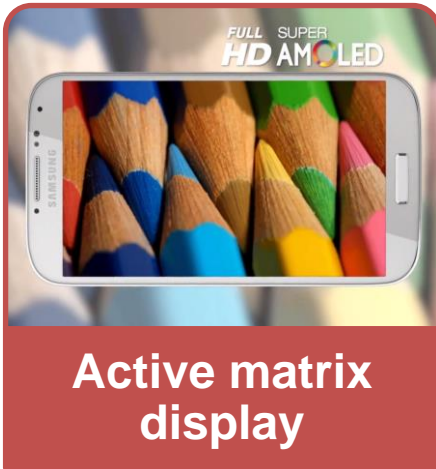


Electronic properties of a-Si:H

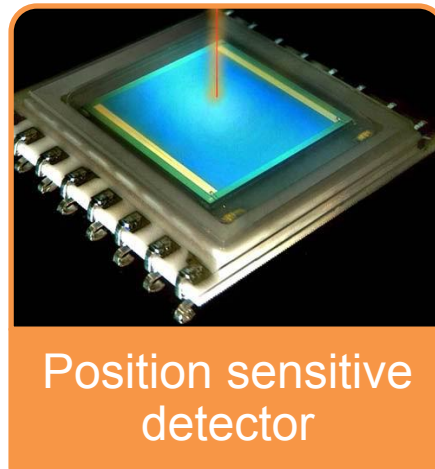
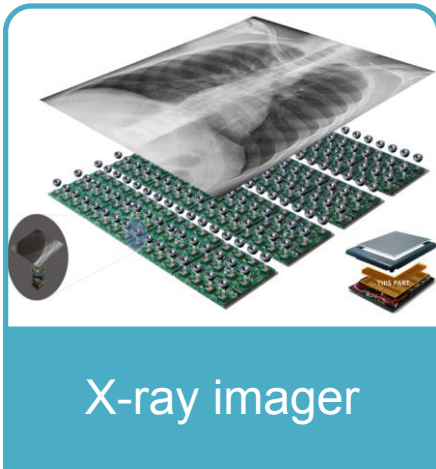
	c-Si (bulk, intrinsic)	a-Si:H (film)
Electron drift mobility	1400 cm ² V ⁻¹ s ⁻¹	1 cm ² V ⁻¹ s ⁻¹
Hole drift mobility	450 cm ² V ⁻¹ s ⁻¹	0.003 cm ² V ⁻¹ s ⁻¹
Carrier diffusion length	> 10 cm	0.3 μm
Undoped conductivity	< 10 ⁻⁵ Ω ⁻¹ cm ⁻¹	10 ⁻¹¹ Ω ⁻¹ cm ⁻¹
Doped conductivity	> 10 ⁴ Ω ⁻¹ cm ⁻¹	Up to 10 ⁻² Ω ⁻¹ cm ⁻¹
Optical band gap	1.1 eV	1.7 eV

- Low carrier mobility: carrier trapping and scattering
- Substitutional doping by PH₃ (n-type) or B₂H₆ (p-type)
- High optical absorption: loss of crystal momentum conservation

Data from R. Street, *Technology and Applications of Amorphous Silicon*
and <http://www.ioffe.rssi.ru/SVA/NSM/Semicond/Si/electric.html>



Amorphous silicon macroelectronics



Position sensitive detector



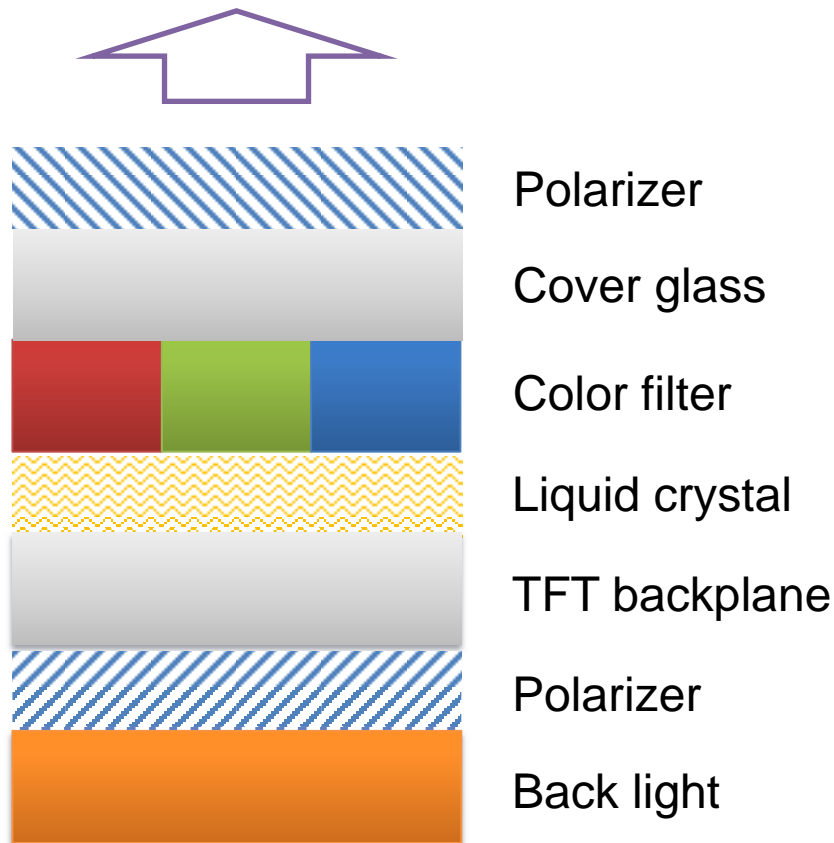
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Passive matrix vs. active matrix (AM) display

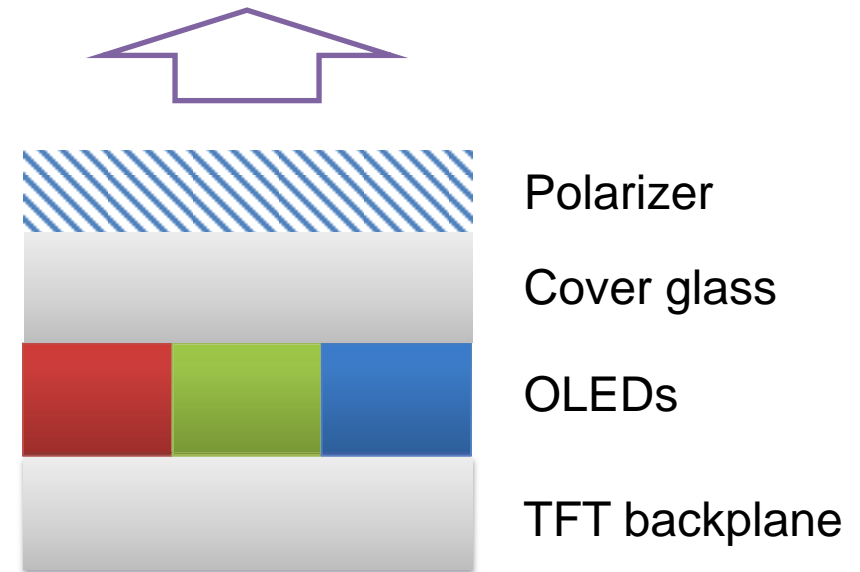
- Passive matrix: $m + n$ control signals address an $m \times n$ display
- Active matrix: each pixel is individually addressed by a transistor
 - High refresh rate
 - Low cross-talk and superior image resolution

OLED Passive Matrix and OLED Active Matrix figures removed due to copyright restrictions. See: [How Stuff Works](#).

Active Matrix Liquid Crystal Display (AMLCD)

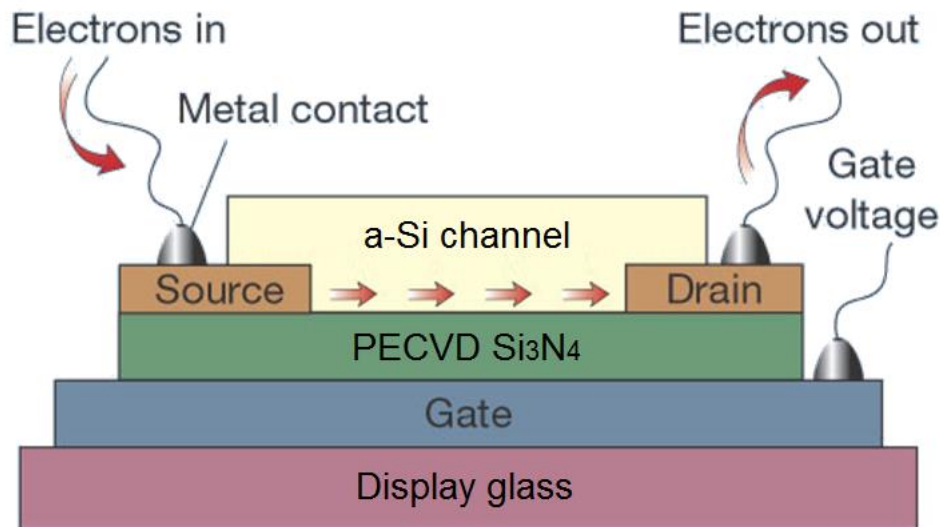


Active Matrix Organic Light Emitting Diode (AMOLED)

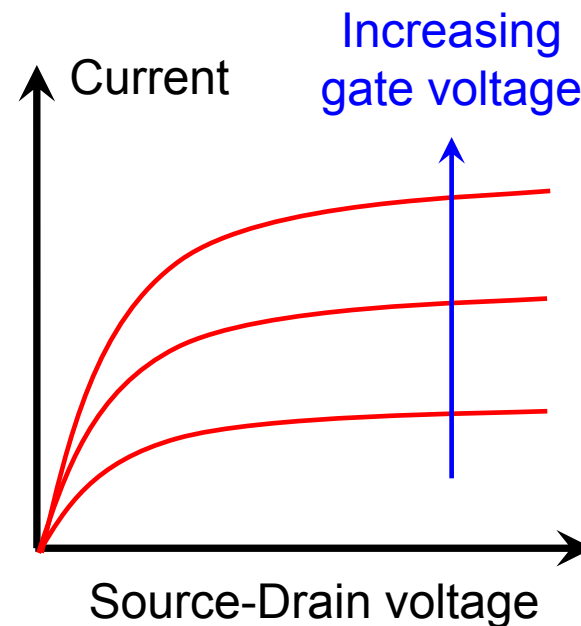


Thin film transistors (TFTs) are made of a-Si or low-temperature poly-silicon (LTPS) obtained by laser annealing of a-Si

a-Si / LTPS thin film transistors



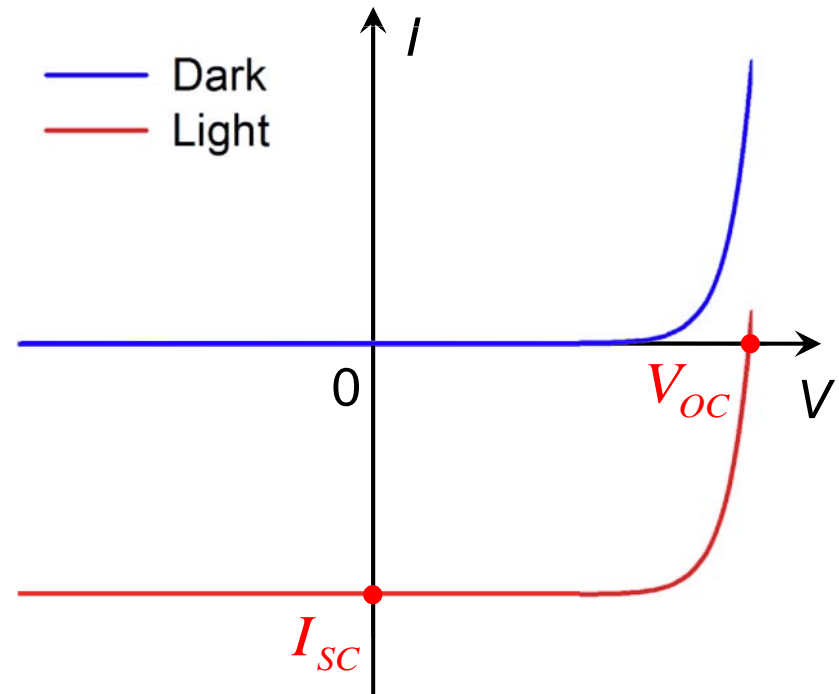
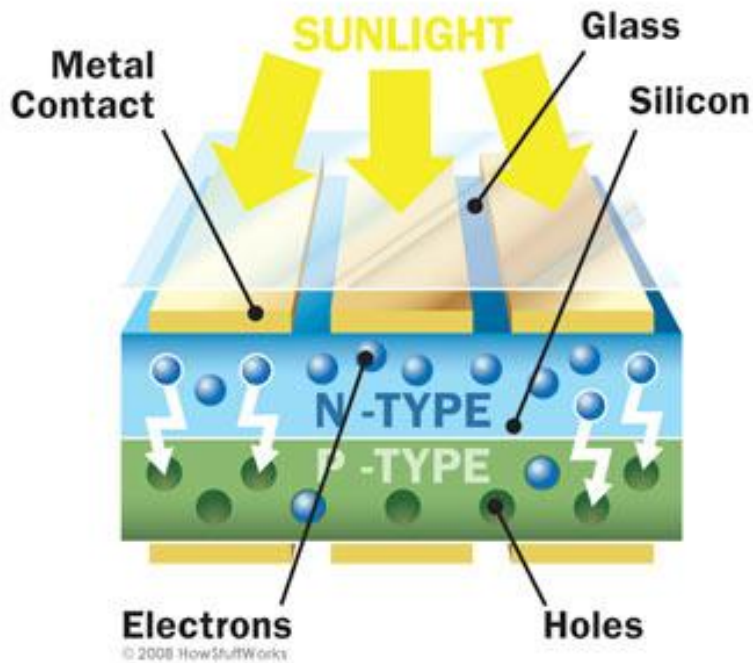
Courtesy of Macmillan Publishers Limited. Used with permission.
Source: Kanatzidis, M.G. "Semiconductor Physics: Quick-set Thin Films." *Nature* 428 (2004): 269-271.



- Applied gate voltage modulates a-Si / LTPS channel conductance and the TFT on/off state
- Si₃N₄ and a-Si can be deposited using the same PECVD system
- Display glass: flat glass produced by down-draw fusion process

Nature 428, 269 (2004)

Basic solar cell structure

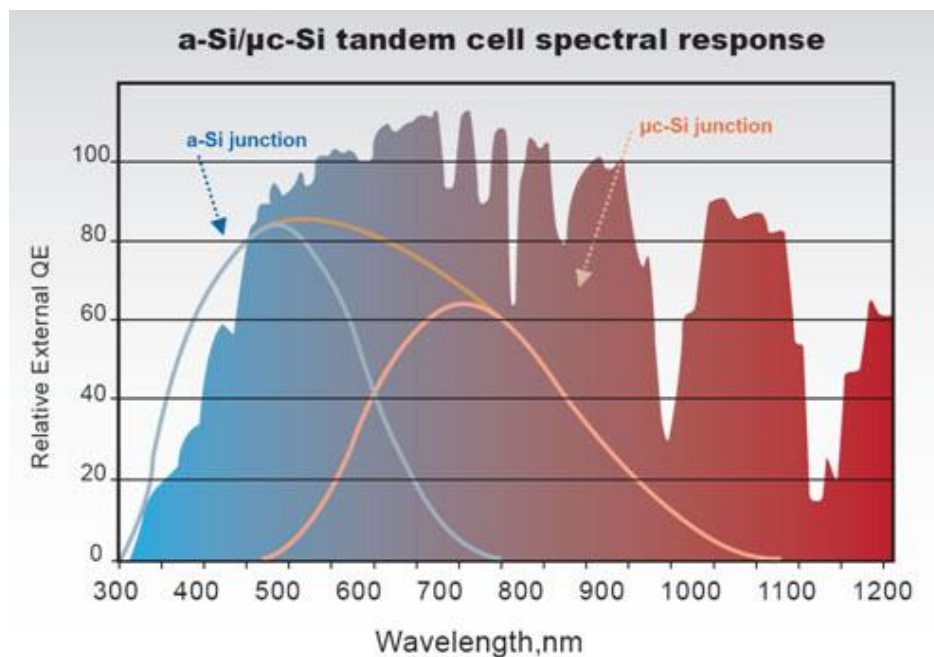
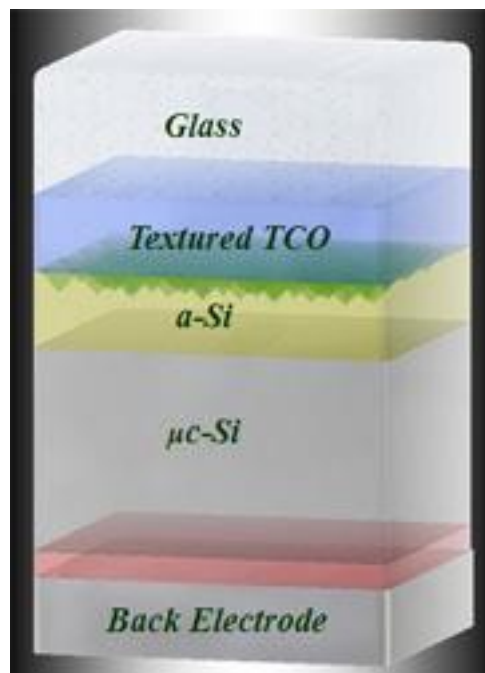


$$I = I_s \cdot \left[\exp\left(\frac{eV}{k_B T}\right) - 1 \right] - I_{sc}$$

I_{sc} : short circuit current
 I_s : diode saturation current

Thin film a-Si:H as a solar absorber

- Large-area, high-throughput deposition
 - High absorption: reduced material consumption
 - Monolithic silicon tandem structures
- } Low cost (?)



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http://www.nexpw.com/Technology/Technology_stt

Staebler-Wronski effect

- Light-induced degradation of hydrogenated a-Si and nano-crystalline Si materials
- Defect generation rate $\propto G^{2/3} t^{1/3}$
- Annealing can partially reverse the effect

Before light
exposure

Figure removed due to copyright restrictions.
See Figure 2: Staebler, D.L. and C.R. Wronski.
"Reversible Conductivity Changes in Discharge-
Produced Amorphous Si." *Applied Physics
Letters* 31 (1977): 292-294.

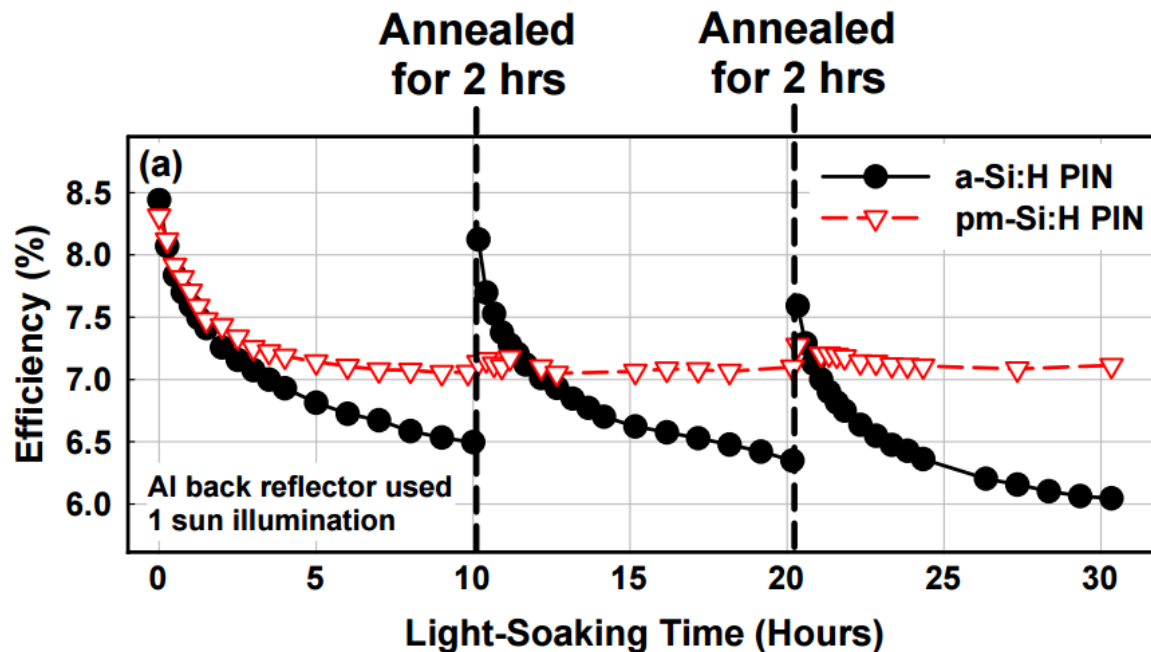
Figure removed due to copyright restrictions. See Figure 6: Stutzmann, M.
et al. "Light-induced Metastable Defects in Hydrogenated Amorphous
Silicon: A Systematic Study." *Phys. Rev. B* 32 (1985): 23-47.

After light
exposure

Appl. Phys. Lett. 31, 292 (1977); *Phys. Rev. B* 32, 23 (1985)

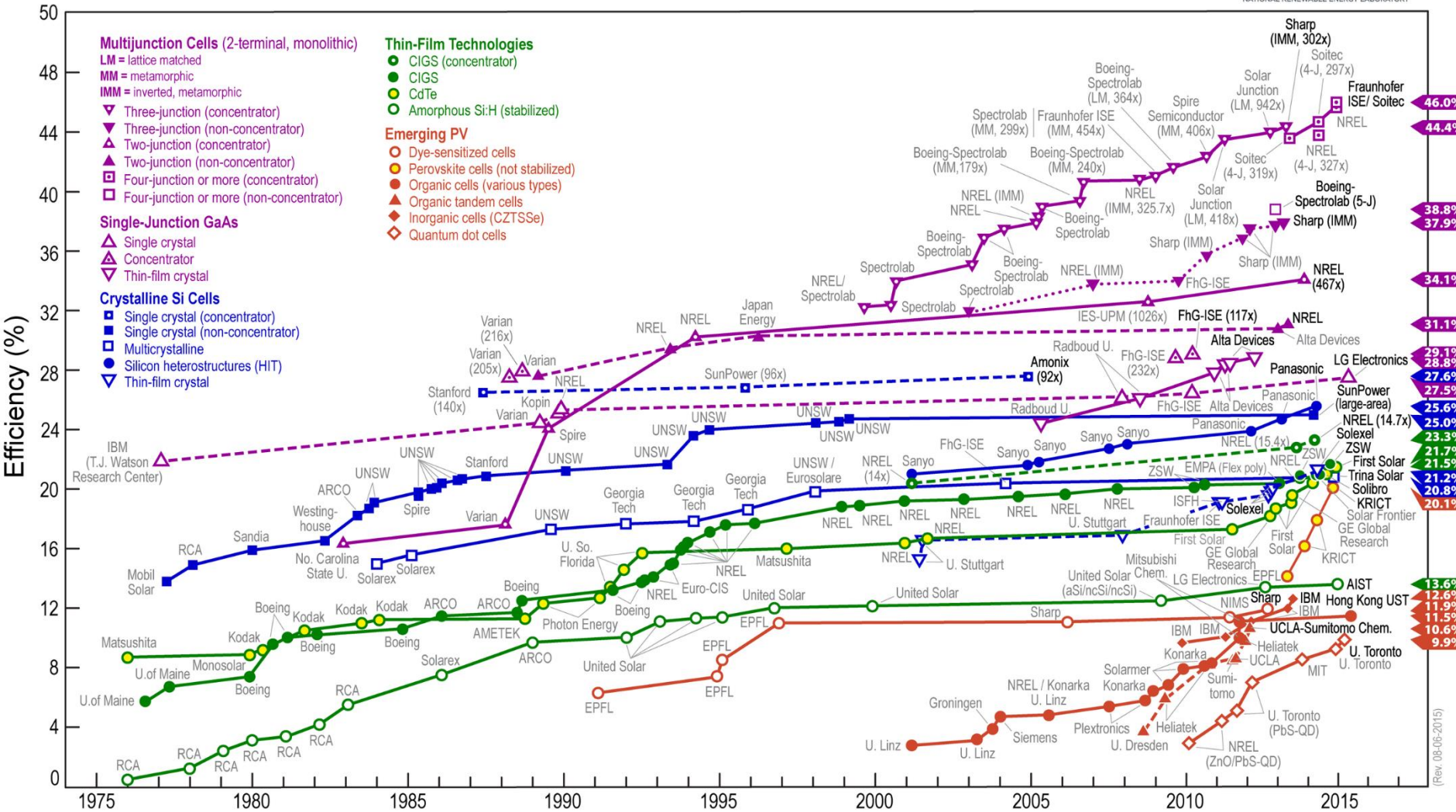
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K. Kim, Diss. Ecole Polytechnique X (2012).

Best Research-Cell Efficiencies



(Rev. 08-06-2015)

Silicon heterojunction (SHJ) cells

Figures of Si diffuse junction cell and Si heterojunction cell removed due to copyright restrictions. See: "[High-efficiency Silicon Heterojunction Solar Cells: A Review](#)." *Green* 2 (2012): 7-24.

- ✓ SHJ reduces recombination at contact surfaces
- ✓ H from a-Si:H passivates c-Si surface

Green 2, 7 (2012)

Summary

- Basic properties of a-Si and a-Si:H
 - Dangling bonds and hydrogenation
 - Electronic properties: Fermi level pinning, factors affecting drift mobility and optical absorption
- Active matrix display based on TFTs
- a-Si solar cells
 - Staebler-Wronski effect

Further Readings

- Springer Handbook of Electronic and Photonic Materials
 - Ch. 25: Amorphous Semiconductors: Structural, Optical, and Electrical Properties
 - Ch. 26: Amorphous and Microcrystalline Silicon
- Technology and Applications of Amorphous Silicon
 - R. A. Street, Springer (2000)

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